



3FV #

PATENT
Attorney Docket No. 02887.0257-00

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)
Akira HAMAGUCHI *et. al.*) Group Art Unit: 2624
Application No.: 10/687,828) Examiner: Vikkram BALI
Filed: October 20, 2003) Confirmation No.: 2967
For: METHOD AND APPARATUS FOR)
DETERMINING DEFECT DETECTION)
SENSITIVITY DATA, CONTROL METHOD)
OF DEFECT DETECTION APPARATUS,)
AND METHOD AND APPARATUS FOR)
DETECTING DEFECT OF)
SEMICONDUCTOR DEVICES)

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

PETITION FOR EXTENSION OF TIME

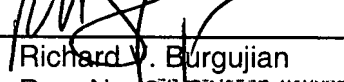
Applicants petition for a three month extension of time to file a reply to the Office Action of January 25, 2007. A fee payment of \$1,020.00 is enclosed.

Please grant any additional extensions of time required to enter the attached reply and charge any additional required fees to Deposit Account 06-0916.

Respectfully submitted,

FINNEGAN, HENDERSON, FARABOW,
GARRETT & DUNNER, L.L.P.

Dated: July 24, 2007

By: 
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